

IN THE CLAIMS:

Claims 1-19 have been amended herein. All of the pending claims 1 through 19 are presented below. This listing of claims will replace all prior versions and listings in the application. Please enter these claims as amended.

1. (Currently Amended) A manufacturing process having data for integrated circuit devices comprising:
storing data and a substantially unique identification code of each integrated circuit device of ~~said~~ the integrated circuit devices at one of at probe testing of ~~said~~ the integrated circuit devices and after probe testing of ~~said~~ the integrated circuit devices, ~~said~~ the data indicating a process flow within ~~said~~ the manufacturing process for each integrated circuit device of ~~said~~ the integrated circuit devices, ~~said~~ storing data comprising:
storing ~~said~~ the substantially unique identification code of ~~said~~ each integrated circuit device of ~~said~~ the integrated circuit devices and a die location on an electronically stored wafer map for each integrated circuit device;
reading ~~said~~ the substantially unique identification code of each integrated circuit device of ~~said~~ the integrated circuit devices;
evaluating ~~said~~ the data for each integrated circuit device of ~~said~~ the integrated circuit devices to said the data for manufacturing process data stored for each integrated circuit device;
identifying integrated circuit devices having a process flow within ~~said~~ the manufacturing process different from ~~said~~ the process flow of ~~said~~ the ~~stored~~ data stored of ~~said~~ the integrated circuit devices; and
directing ~~said~~ each the integrated circuit ~~device~~ devices of ~~said~~ integrated circuit devices identified as having a process flow within ~~said~~ the manufacturing process different from ~~said~~ the process flow of ~~said~~ stored the data stored of ~~said~~ the integrated circuit devices to another process.

2. (Currently Amended) The process of claim 1, wherein ~~said~~ storing data comprises storing data at a probe.

3. (Currently Amended) The process of claim 1, wherein ~~said~~ storing data comprises storing data and ~~said~~ the substantially unique identification code of ~~said~~ each integrated circuit device of ~~said~~ the integrated circuit devices to indicate each integrated circuit device of ~~said~~ the integrated circuit devices comprises one of a good integrated circuit device and a bad integrated circuit device.

4. (Currently Amended) The process of claim 1, wherein ~~said~~ reading ~~said~~ the substantially unique identification code of each integrated circuit device of ~~said~~ the integrated circuit devices comprises electrically retrieving a unique fuse identification programmed into ~~said~~ each integrated circuit device of ~~said~~ the integrated circuit devices.

5. (Currently Amended) The process of claim 1, wherein ~~said~~ reading ~~said~~ the substantially unique identification code of each integrated circuit device of ~~said~~ the integrated circuit devices comprises optically reading a unique identification code on each integrated circuit device of ~~said~~ the integrated circuit devices.

6. (Currently Amended) The process of claim 5, wherein ~~said~~ optically reading ~~said~~ the unique identification code ~~provided~~ on each integrated circuit device of ~~said~~ the integrated circuit devices comprises optically reading a unique laser fuse identification programmed into each integrated circuit device of ~~said~~ the integrated circuit devices.

7. (Currently Amended) The process of claim 1, wherein ~~said~~ reading ~~said~~ the substantially unique identification code of each integrated circuit device of ~~said~~ the integrated circuit devices comprises reading ~~said~~ the substantially unique identification code of ~~said~~ each

integrated circuit device of ~~said~~ the integrated circuit devices at an opens/shorts test in ~~said~~ the manufacturing process.

8. (Currently Amended) The process of claim 1, wherein ~~said~~ the stored data ~~stored~~ and ~~said~~ the substantially unique identification code of ~~said~~ each integrated circuit device of ~~said~~ the integrated circuit devices ~~is~~ are accessed by accessing ~~said~~ the stored data ~~stored~~ and ~~said~~ the substantially unique identification code of ~~said~~ each integrated circuit device of ~~said~~ the integrated circuit devices at an opens/shorts test in ~~said~~ the manufacturing process.

9. (Currently Amended) The process of claim 8, wherein ~~said~~ evaluating ~~said~~ the data comprises evaluating ~~said~~ the data ~~accessed~~ for ~~said~~ each integrated circuit device of ~~said~~ the integrated circuit devices to identify any bad integrated circuit devices having undergone an assembly procedure within ~~said~~ the manufacturing process.

10. (Currently Amended) The process of claim ~~8~~ 9, wherein ~~said~~ evaluating ~~said~~ the data comprises evaluating ~~said~~ the data at an opens/shorts test in ~~said~~ the manufacturing process.

11. (Currently Amended) The process of claim 1, wherein ~~said~~ directing ~~said~~ each the integrated circuit ~~device~~ devices of ~~said~~ integrated circuit devices identified as having a process flow within ~~said~~ the manufacturing process different from ~~said~~ the process flow of ~~said~~ the stored data of ~~said~~ the integrated circuit devices to another process comprises discarding any integrated circuit device identified as having a process flow within ~~said~~ the manufacturing process different from ~~said~~ the process flow of ~~said~~ the stored data.

12. (Currently Amended) The process of claim 1, wherein ~~said~~ directing occurs before a back-end test procedure within ~~said~~ the manufacturing process.

13. (Currently Amended) The process of claim 1, further comprising assembling-~~said~~ the integrated circuit devices into packaged integrated circuit devices after storing data and before reading-~~said~~ the substantially unique identification code of ~~said~~-each integrated circuit device of-~~said~~ the integrated circuit devices.

14. (Currently Amended) A method of manufacturing integrated circuit devices comprising:
providing a plurality of semiconductor wafers, each semiconductor wafer having a plurality of integrated circuit devices thereon, ~~said~~ the integrated circuit devices comprising:
integrated circuit devices selected from a group comprising Dynamic Random Access Memory (DRAM) devices, Static Random Access Memory (SRAM) devices, synchronous DRAM (SDRAM) devices, and processor devices;
storing a substantially unique identification code in each integrated circuit device of-~~said~~ the plurality of integrated circuit devices on-~~said~~ each semiconductor wafer of-~~said~~ the plurality of semiconductor wafers;
storing data and-~~said~~ the substantially unique identification code of ~~said~~-each integrated circuit device of-~~said~~ the plurality of integrated circuit devices indicating manufacturing processes for ~~said~~-each integrated circuit device of-~~said~~ the plurality of integrated circuit devices at one of probe testing and after probe testing of-~~said~~ the plurality of integrated circuit devices;
separating ~~said~~-each integrated circuit device of-~~said~~ the plurality of integrated circuit devices on ~~said~~ each semiconductor wafer of-~~said~~ the plurality of semiconductor wafers to form-~~said~~ an integrated circuit device of-~~said~~ a plurality of integrated circuit devices;
assembling ~~said~~-each integrated circuit device of-~~said~~ the plurality of integrated circuit devices into an integrated circuit device assembly;
reading ~~said~~-the substantially unique identification code of ~~said~~-each integrated circuit device of ~~said~~ the integrated circuit device assemblies;

evaluating data for ~~said~~ each integrated circuit device of ~~said~~ the integrated circuit device assemblies identifying any integrated circuit devices having undergone any manufacturing process different from ~~said~~ the indicated manufacturing processes of ~~said~~ the stored data for ~~said~~ each integrated circuit device;
subjecting to further processing ~~said~~ the integrated circuit ~~device~~ devices of ~~said~~ the plurality of integrated circuit devices identified as having undergone a manufacturing process different from ~~said~~ the indicated manufacturing processes of its stored data; and
back-end testing integrated circuit devices not subjected to further processing.

15. (Currently Amended) The method of claim 14, further comprising programming ~~said~~ each integrated circuit device of ~~said~~ the plurality of integrated circuit devices on ~~said~~ each semiconductor wafer of ~~said~~ the plurality of semiconductor wafers to permanently store a unique fuse identification.

16. (Currently Amended) The method of claim 15, wherein ~~said~~ programming ~~said~~ each integrated circuit device of ~~said~~ the plurality of integrated circuit devices on ~~said~~ each semiconductor wafer of ~~said~~ the plurality of semiconductor wafers to permanently store ~~said~~ the unique fuse identification comprises programming at least one of fuses and anti-fuses in ~~said~~ each integrated circuit device of ~~said~~ the plurality of integrated circuit devices on ~~said~~ each semiconductor wafer of ~~said~~ the plurality of semiconductor wafers to permanently store ~~said~~ the unique fuse identification.

17. (Currently Amended) The method of claim 14, wherein ~~said~~ assembling ~~said~~ each integrated circuit device of ~~said~~ the plurality of integrated circuit devices into an integrated circuit device assembly comprises:
picking each integrated circuit device of ~~said~~ the plurality of integrated circuit devices from its semiconductor wafer of ~~said~~ the plurality of semiconductor wafers;

placing ~~said~~ each integrated circuit device of ~~said~~ the plurality of integrated circuit devices onto an epoxy-coated bonding site of one of a plurality of lead frames;
curing ~~said~~ the epoxy on ~~said~~ the bonding site of each one of ~~said~~ the plurality of lead frames;
wire bonding ~~said~~ each integrated circuit device of ~~said~~ the plurality of integrated circuit devices to its associated lead frame;
injection molding ~~said~~ each integrated circuit device of ~~said~~ the plurality of integrated circuit devices and its associated lead frame to form one of a plurality of integrated circuit device packages, each having projecting leads;
deflashing ~~said~~ the projecting leads of each integrated circuit device package of ~~said~~ the plurality of integrated circuit device packages;
curing ~~said~~ each integrated circuit device package of ~~said~~ the plurality of integrated circuit device packages;
electroplating ~~said~~ the projecting leads of ~~said~~ each integrated circuit device package of ~~said~~ the plurality of integrated circuit device packages;
singulating ~~said~~ each integrated circuit device package of ~~said~~ the plurality of integrated circuit device packages into one of a plurality of discrete integrated circuit devices; and
testing ~~said~~ each discrete integrated circuit device of ~~said~~ the plurality of discrete integrated circuit devices for opens and shorts.

18. (Currently Amended) The method of claim 14, wherein ~~said~~ assembling ~~said~~ each integrated circuit device of ~~said~~ the plurality of integrated circuit devices into an integrated circuit device assembly comprises assembling ~~said~~ each integrated circuit device of ~~said~~ the plurality of integrated circuit devices into an integrated circuit device selected from a group comprising a wire bond/lead frame integrated circuit device, a Chip-On-Board (COB) integrated circuit device, a flip-chip integrated circuit device, and a Tape-Automated Bonding (TAB) integrated circuit device.

19. (Currently Amended) A method of manufacturing Multi-Chip Modules comprising:

providing a plurality of integrated circuit devices on a semiconductor wafer of a plurality of semiconductor wafers;

storing a substantially unique identification code in each integrated circuit device of ~~said the~~ plurality of integrated circuit devices on ~~said each semiconductor wafer of the plurality of semiconductor wafers~~ at one of probe testing and after probe testing;

storing data and ~~said the~~ substantially unique identification code of ~~said each integrated circuit device of said the~~ plurality of integrated circuit devices indicating desired manufacturing processes for ~~said each integrated circuit device of said the~~ plurality of integrated circuit devices;

separating ~~said each integrated circuit device of said the~~ plurality of integrated circuit devices on ~~said each semiconductor wafer of said a~~ plurality of semiconductor wafers from ~~said each semiconductor wafer to form one of said a~~ plurality of integrated circuit devices;

assembling one or more integrated circuit devices of ~~said the~~ plurality of integrated circuit devices into each of a plurality of multi-chip modules, ~~said the~~ plurality of multi-chip modules selected from a group comprising Single In-Line Memory Modules (SIMM's) and Dual In-line Memory Modules (DIMM's);

reading ~~said the~~ substantially unique identification code of ~~said each integrated circuit device of said the~~ plurality of integrated circuit devices in ~~said each of said the~~ plurality of multi-chip modules;

evaluating data for ~~said each integrated circuit device of said the~~ plurality of integrated circuit devices in ~~said each of said the~~ plurality of multi-chip modules identifying any multi-chip modules having integrated circuit devices having undergone a manufacturing process that is different from ~~said the~~ desired manufacturing ~~process processes of said manufacturing processes~~;

redirecting any multi-chip modules identified as having integrated circuit devices having undergone ~~said the~~ manufacturing process that is different from ~~said the~~ desired

manufacturing ~~process~~ processes ~~of said manufacturing process~~; and
back-end testing any nonredirected multi-chip modules.